

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Toru TOJO, et al.

SERIAL NO.: New Application

FILED: Herewith

FOR: PATTERN INSPECTION APPARATUS

**STATEMENT OF RELEVANCY**

**Reference AA (5,572,598) of Form PTO-1449:**

This reference shows an optical system illuminated by a scanning laser, in which individual transmitted and reflected light and detectors are used to inspect the defects.

**Reference AB (5,563,702) of Form PTO-1449:**

This reference shows an inspection method using transmitted and reflected signals from the substrate.

**Reference AO (2002-501194) of Form PTO-1449:**

This reference shows an inspection system which can detect transmitted and reflected light simultaneously.

**Reference AW of Form PTO-1449:**

The cell-to-cell comparison method to obtain high defect detection sensitivity is studied in this paper. Transmission and reflection optics are used.